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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	JEROMINEK	Examiner:	J. RUGGLE
Serial No.:	09/888,989	Group Art Unit:	1756
Filed:	JUNE 25, 2001	Docket No.:	9680.173USU1
Title:	METHOD OF FABRICATING A SUSPENDED MICRO-STRUCTURE WITH A SLOPED SUPPORT AND A SUSPENDED MICROSTRUCTURE FABRICATED BY THE METHOD		

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited in the United States Postal Service, as first class mail, with sufficient postage, in an envelope addressed to: ~~Mail Stop Non-Fee Amendment~~ Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on May 16, 2003.

By:

Name: Teresa D. Morgan

AMENDMENT

~~Mail Stop Non-Fee Amendment~~

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated February 4, 2003, please amend the above-referenced application as follows:

In the Claims

Please amend claims 1, 4 and 15 as follows:

1. (Amended) A method of fabricating a suspended microstructure with a sloped support, comprising the steps of:

(a) providing a member having three stacked up layers including a first substrate layer, a second temporary layer and a third photoresist layer;

B<sub>1</sub> (b) photolithographically transferring a sloped pattern to the third photoresist layer by means of a grey scale mask;

(c) etching the second layer through the third layer resulting from step (b) to obtain a surface with at least one continuous slope with a predetermined angle with respect to the first substrate layer;